

**PATENT APPLICATION**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of

Docket No: Q90606

Akira KOBAYASHI, et al.

Appln. No.: 10/550,897

Group Art Unit: 2812

Confirmation No.: 1704

Examiner: Kevin M. PICARDAT

Filed: September 27, 2005

For: CHEMICAL VAPOR DEPOSITED FILM BASED ON A PLASMA CVD METHOD  
AND MEHTOD OF FORMING THE FILM

**AMENDMENT UNDER 37 C.F.R. § 1.111**

**MAIL STOP AMENDMENT**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

A petition and the required fee for a two month extension of time are being submitted herewith to extend the time period from April 14, 2008 to June 16, 2008 (June 14, 2008 being a Saturday).

In response to the Office Action dated January 14, 2008, please amend the above-identified application as follows on the accompanying pages.

**TABLE OF CONTENTS**

AMENDMENTS TO THE SPECIFICATION .....	2
AMENDMENTS TO THE CLAIMS .....	3
REMARKS .....	7